

Title (en)
Layered structure and process for producing a layered structure

Title (de)
Schichtstruktur und Verfahren zur Herstellung einer Schichtstruktur

Title (fr)
Structure stratifiée et procédé pour sa production

Publication
EP 1496140 A1 20050112 (DE)

Application
EP 03015495 A 20030709

Priority
EP 03015495 A 20030709

Abstract (en)
Layer structure (1) comprises a partially porous partially gas-permeable layer (7) arranged on a substrate (4). The porous layer has pores (10) delimited by walls (37) with a coating (40) formed on the walls. An independent claim is also included for a process for the production of the layer structure.

Abstract (de)
Schichtstrukturen nach dem Stand der Technik weisen eine nicht so effiziente Kühlung gegen ein äußeres heißes Gas auf. Die erfindungsgemäß ausgebildete Schichtstruktur (1) weist neben einer porösen Schicht (7) zumindest teilweise eine Beschichtung (40) innerhalb der Schicht (7) auf. Somit wird die Kühlung und der Schutz vor zu hohem Wärmeeintrag in die Schichtstruktur (1) verbessert. <IMAGE>

IPC 1-7
C23C 28/00; F01D 5/28; F01D 5/18

IPC 8 full level
C23C 28/00 (2006.01); **C23C 30/00** (2006.01); **F01D 5/18** (2006.01); **F01D 5/28** (2006.01)

CPC (source: EP US)
C23C 28/042 (2013.01 - EP US); **C23C 28/3215** (2013.01 - EP US); **C23C 28/322** (2013.01 - EP US); **C23C 28/345** (2013.01 - EP US); **C23C 28/3455** (2013.01 - EP US); **C23C 30/00** (2013.01 - EP US); **F01D 5/183** (2013.01 - EP US); **F01D 5/288** (2013.01 - EP US); **Y10T 428/249954** (2015.04 - EP US); **Y10T 428/249955** (2015.04 - EP US); **Y10T 428/249956** (2015.04 - EP US); **Y10T 428/249961** (2015.04 - EP US); **Y10T 428/249967** (2015.04 - EP US); **Y10T 428/24997** (2015.04 - EP US); **Y10T 428/24999** (2015.04 - EP US)

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Designated contracting state (EPC)
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IT LI LU MC NL PT RO SE SI SK TR

DOCDB simple family (publication)
EP 1496140 A1 20050112; CN 100540743 C 20090916; CN 1816646 A 20060809; DE 502004004097 D1 20070726; EP 1641959 A1 20060405; EP 1641959 B1 20070613; ES 2287758 T3 20071216; PL 1641959 T3 20071031; US 2006153685 A1 20060713; US 7402335 B2 20080722; WO 2005005688 A1 20050120

DOCDB simple family (application)
EP 03015495 A 20030709; CN 200480018893 A 20040617; DE 502004004097 T 20040617; EP 04763007 A 20040617; EP 2004006556 W 20040617; ES 04763007 T 20040617; PL 04763007 T 20040617; US 56394804 A 20040617